

# Low-Power and High-Speed Operation Capabilities of Semiconductor Membrane Lasers – Energy Cost Limited by Joule Heat

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**Short-Abstract**—The power consumption of a lateral current injection (LCI) type membrane distributed reflector (DR) laser under a high-speed direct modulation was theoretically investigated. As the results, we found that there is an optimal cavity length, which can be determined by the series resistance, to minimize the power consumption. For an example, an energy cost of 37 fJ/bit can be obtained at a modulation speed of 10 Gb/s for the cavity length of 17  $\mu\text{m}$  when the grating coupling coefficient of 1800  $\text{cm}^{-1}$  and the resistivity of  $p$ -InP cladding layer of 0.035  $\Omega\cdot\text{cm}$  are used.

## I. INTRODUCTION

Optical interconnects provide significant performance improvement and power savings over copper-based solutions in conventional large-scale integrated circuits (LSIs) [1]. Here in the case of global on-chip wiring, we should aim at targeted energy of  $\sim 100\text{fJ/bit}$  [2]. For this purpose, on-chip light sources with low power consumption, such as VCSELs [3] and photonic crystal lasers [4, 5], have been reported in recent years. In particular, the ultra-low energy operation of 4.4 fJ/bit was demonstrated in a system combining the photonic crystal laser and an avalanche photo diode (APD) [6]. However, in the receiver side, the use of PIN photodiodes instead of APDs is recommended from the viewpoint of a total system power consumption. Therefore, it is strongly desired to realize on-chip lasers with low power consumption and with sufficient output power for error-free operations using a PIN photodiode.

Toward the above target, we have proposed a semiconductor membrane laser [7] and demonstrated room-temperature continuous-wave (RT-CW) operation under current injection [8]. The membrane structure consists of a thin semiconductor core layer sandwiched by much lower refractive-index materials such as  $\text{SiO}_2$ , BCB, and air. This high index-contrast structure enables to realize strong optical confinement into the active region, and results in low threshold current operation. Further, we can control the light output by introducing the grating structure in the semiconductor membrane laser.

In this work, we show fundamental performance of a membrane distributed-reflector (DR) laser for low power consumption operation under a high-speed direct modulation condition. Moreover the cavity length dependence of energy cost for 10 Gb/s data transmission is theoretically given by taking into account the Joule heat in the series resistance. As

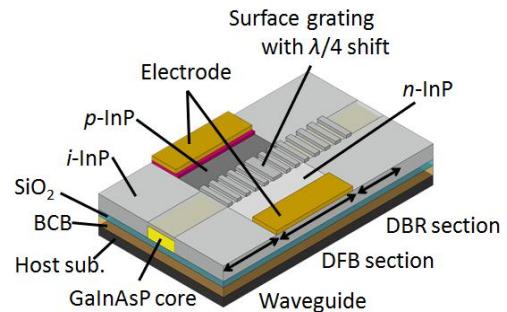


Fig. 1 Schematic view of a LCI membrane DR laser

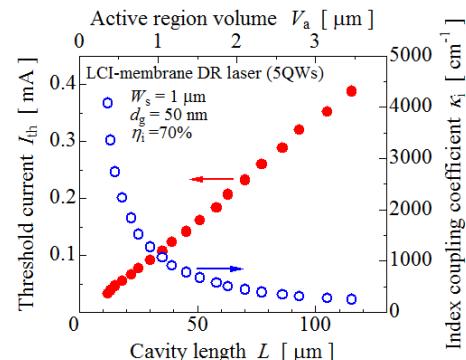


Fig. 2 Cavity length dependence of threshold current  $I_{\text{th}}$  for various index coupling coefficients.

the result, it is shown that the increase of power consumption in the Joule heat limits the low power consumption operation.

## II. ANALYSIS OF SEMICONDUCTOR MEMBRANE DR LASER

The structure of a lateral current injection type membrane-DR (LCIM-DR) laser is shown in Fig. 1. The DR structure consists of DFB section including active layer and distributed-Bragg-reflector (DBR) section [9]. In the calculation, we assumed a DBR with the reflectivity of 99% at the one side of the laser cavity, and introduced  $\lambda/4$  phase-shift in the DFB section to reduce the threshold current.

As analysis of the performances, we calculated the minimum threshold current for a given index-coupling coefficient  $\kappa_i$  of the LCIM-DR laser with surface grating structure as shown in Fig. 2. The index-coupling coefficient  $\kappa_i$  was determined by varying core thickness with a fixed grating depth  $d_g = 50 \text{ nm}$ . The stripe width  $W_s$  and the internal

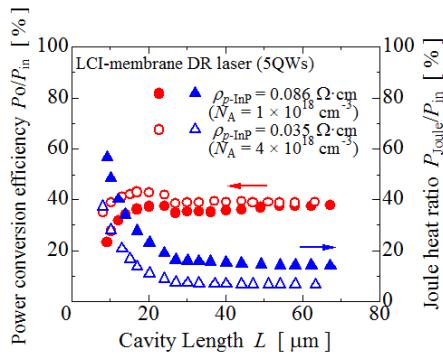


Fig. 4 Power conversion efficiency and Joule heat ratio for different resistivities.

quantum efficiency  $\eta_i$  were assumed to 1  $\mu\text{m}$  and 70%, respectively. As can be seen, the threshold current decreases with a decrease of the cavity length, and a threshold current of 32  $\mu\text{A}$  can be obtained for a cavity length of 10  $\mu\text{m}$  and  $\kappa_i$  of 4000  $\text{cm}^{-1}$  ( $d_{\text{core}} = 150 \text{ nm}$ ). This result simply shows that a shorter cavity with high index-coupling coefficient is required for ultralow threshold current operation.

### III. POWER CONSUMPTION AND JOULE HEAT

An ultra-low energy cost of less than 100 fJ/bit is required for the light source for on-chip optical interconnection as mentioned previously. Furthermore, there is a requirement for light output determined by the minimum receivable power of a photo-detector and a link loss including coupling loss between each device and waveguide loss. We used the minimum receivable power of -13 dBm (0.05 mW) which is usually used for an average performance GaInAs *p-i-n* photodiode (PIN-PD) at 10 Gb/s operation and the link loss was assumed to be 5 dB, hence the required light output was estimated to be -8 dBm (0.16 mW) for a 10 Gb/s transmission.

For estimation of total power consumption of the LCIM-DR laser, we assumed *p*-InP cladding layer resistance as the device resistance because it is dominant in the total resistance. Fig. 4 shows cavity length dependences of the power conversion efficiency and Joule heat ratio of the LCIM-DR laser. In the case of *p*-InP cladding layer resistivity of  $\rho_{p-\text{InP}} = 0.086 \Omega\cdot\text{cm}$  (the doping concentration of  $N_A = 1 \times 10^{18}/\text{cm}^3$ ) calculated from *p*-InP mobility [10], the Joule heat is remarkable for the cavity length of less than 20  $\mu\text{m}$ . However, it can be reduced to less than half by increasing  $N_A$  to  $4 \times 10^{18}/\text{cm}^3$  ( $\rho_{p-\text{InP}} = 0.035 \Omega\cdot\text{cm}$ ), and it will suppress the drastic decrease of power conversion efficiency in very short cavity length range.

Finally, we estimated an energy cost for 10 Gb/s data transmission for various cavity lengths (and  $\kappa_i$ ) as shown in Fig. 5. As can be seen, the energy cost of less than 100 fJ/bit can be obtained with the cavity length of less than 50  $\mu\text{m}$ , and the minimum energy cost of 37 fJ/bit can be obtained for the cavity length of 17  $\mu\text{m}$  ( $\kappa_i = 1800 \text{ cm}^{-1}$ ).

### IV. CONCLUSION

We theoretically investigated the operation energy of LCIM-DR lasers for low-power and high-speed operation. The threshold current of 32  $\mu\text{A}$  can be obtained by shortening the

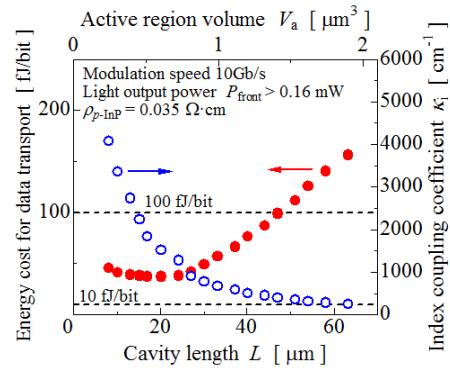


Fig. 5 Cavity length dependence of energy cost for various index coupling coefficients.

cavity length to 10  $\mu\text{m}$ , however, there is an optimal cavity length to minimize the energy cost, and the minimum energy cost of 37 fJ/bit can be obtained with the cavity length of 17  $\mu\text{m}$ . This means that the power consumption is limited by Joule heat in short cavity length lasers.

### ACKNOWLEDGMENT

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### REFERENCES

- [1] D. A. B. Miller, "Rationale and challenges for optical interconnects to electronic chips," *Proc. IEEE*, vol. 88, no. 6, pp. 728–749, June 2000.
- [2] D. A. B. Miller, "Device requirements of optical interconnects to silicon chips," *Proc IEEE*, vol. 97, no. 7, pp. 1166–1185, July 2009.
- [3] P. Moser, W. Hofmann, P. Wolf, J. A. Lott, G. Larisch, A. Payusov, N. N. Ledentsov, and D. Bimberg, "81 fJ/bit energy-to-data ratio of 850 nm vertical-cavity surface emitting lasers for optical interconnects," *Appl. Phys. Lett.*, vol. 98, no. 23, pp. 231106-1–3, June, 2011.
- [4] S. Matsuo, A. Shinya, Chin-Hui Chen, K. Nozaki, T. Sato, Y. Kawaguchi, H. Taniyama, and M. Notomi, "20-Gbit/s directly modulated photonic crystal nanocavity laser with ultra-low power consumption," *Optics Express*, vol. 19, no. 3, pp. 2242–2250, Jan. 2011.
- [5] B. Ellis, M. A. Mayer, G. Shambat, T. Sarmiento, J. Harris, E. E. Haller, and J. Vučković, "Ultralow-threshold electrically pumped quantum-dot photonic-crystal nanocavity laser," *Nature Photonics*, vol. 5, no. 5, pp. 297–300, May 2011.
- [6] K. Takeda, T. Sato, A. Shinya, K. Nozaki, W. Kobayashi, H. Taniyama, M. Notomi, K. Hasebe, T. Kakitsuka, and S. Matsuo, "Few-fJ/bit data transmissions using directly modulated lambda-scale embedded active region photonic-crystal lasers," *Nature Photonics*, vol. 7, no. 7, pp. 569–575, July, 2013.
- [7] S. Sakamoto, H. Naitoh, M. Ohtake, Y. Nishimoto, T. Maruyama, N. Nishiyama, and S. Arai, "85 °C continuous-wave operation of GaInAsP/InP-membrane buried heterostructure distributed feedback lasers with polymer cladding layer," *Jpn. J. Appl. Phys.*, vol. 46, no. 47, pp. L1155–L1157, Nov. 2007.
- [8] K. Doi, T. Shindo, M. Futami, J. Lee, T. Hiratani, D. Inoue, S. Yang, T. Amemiya, N. Nishiyama, and S. Arai, "Room-temperature continuous-wave operation of lateral current injection membrane laser," *The 25th International Conference on Indium Phosphide and Related Materials (IPRM 2013)*, Kobe, Japan, Wed2-3, May 2013.
- [9] J. I. Shim, K. Komori, S. Arai, I. Arima, Y. Suematsu, and R. Somchai, "Lasing characteristics of 1.5  $\mu\text{m}$  GaInAsP-InP SCH-BIG-DR lasers," *IEEE J. Quantum Electron.*, vol. 27, no. 6, pp. 1736–1745, June 1991.
- [10] M. Sotoodeh, A. H. Khalid, and A. A. Rezaazadeh, "Empirical low-field mobility model for III-V compounds applicable in device simulation codes," *J. Appl. Phys.*, vol. 87, no. 6, pp. 2890–2900, Mar. 2000.